

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Etsuko ASANO et al.

Application No.: 10/735,627

Filed: December 16, 2003

For: An Evaluation Method using a TEG, A Method of  
manufacturing a Semiconductor Device Having the TEG, An  
Element Substrate and A Pannel Having the TEG, A Program for  
Controlling Dosage and A Computer-Readable Recording Medium  
recording the Program

)  
)  
)  
) Examiner: Unknown  
)  
) Group Art Unit:  
)  
) Not Yet Assigned  
)  
)  
)  
)

VERIFICATION OF TRANSLATION

P. O. Box 1450  
Alexandria VA 22313-1450

Sir:

I, Mika Tatsumi, C/O Semiconductor Energy Laboratory Co., Ltd. 398, Hase, Atsugi-shi,  
Kanagawa-ken 243-0036 Japan, a translator, herewith declare:

that I am well acquainted with both the Japanese and English Languages;

that I am the translator of the attached translation of the US Patent Application No. 10/735,627 filed  
on December 16, 2003; and

that to the best of my knowledge and belief the followings is a true and correct translation of the US  
Patent Application No. 10/735,627 filed on December 16, 2003.

I further declare that all statements made herein of my own knowledge are true and that all statements  
made on information and belief are believed to be true; and further that these statements were made with the  
knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both,  
under Section 1001 of Title 18 of the United States Code, and that such willful false statements may  
jeopardize the validity of the application or any patent issuing thereon.

Date: this 23<sup>rd</sup> day of July, 2004

Mika Tatsumi

Name: Mika Tatsumi